

Title (en)

METHOD OF MANUFACTURING A GAS SENSOR

Title (de)

VERFAHREN ZUR HERSTELLUNG EINES GASSENSORS

Title (fr)

PROCEDE DE FABRICATION D'UN DETECTEUR DE GAZ

Publication

EP 0722564 A1 19960724 (DE)

Application

EP 95927641 A 19950807

Priority

- DE 9501035 W 19950807
- DE 4428155 A 19940809

Abstract (en)

[origin: DE4428155A1] In order to increase the conductivity of gas sensors used for detecting reducing gases, a Ga₂O₃ layer (A) is applied to a substrate (S) to act as the gas-sensitive layer and tempered at a temperature of between 750 and 850 DEG C to ensure that the Ga₂O₃ layer is free of acceptors.

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